FORM PTQ-1449 (REV.7-80)			U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			A;;;; Docine: 1:0:		9/616,794	/616,794		
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ScM		м	6,254,459 B1	07/03/01	Bajaj et a	l	451	41			
		ΑВ	6,454,630 B1	09/24/02	Tolles		451	6			
		AC	6,458,014 B1	10/01/02	Ihsikawa	et al.	451	6	-		
		ΑD	6,607,422 B1	08/19/03	Swedek e	t al.	451	6			
		ΑE	6,612,901 Bl	09/02/03	Agarwal		451	6			
54	LM AF 20010044261 A1		11/22/01 Elledge			451	41' RE	CEIV	ED		
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FORM PTO-1449 (REV.7-80)			U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. 500188.02		APPLICATION NO. 09/616,794				
INFORMATION DISCLOSURE STATEMENT						APPLICANT(S) Jason B. Elledge						
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EXAMINER INTELL		nenii)	FORCUMENT NUMBER	DATE	NAME		CLASS		SUBCLASS	IF APPROPRIATE		
SLM		AA	6,426,232	07/30/02	Litvak		438		8			
		AB	6,323,046	11/27/01	Agarwal		438		8/			
-		AC	6,285,035	09/04/01	Taravade		250		559.22			
		AD	6,241,847	06/05/01	Allman et al.		438		8			
		AE	6,121,147	09/19/00	Daniel et	438		692				
		AF	6,074,517	06/13/00	Taravade				345.13			
		AG	5,948,203	09/07/99	Wang				345.03			
		AH	5,872,633	02/16/99	Holzapfel	et al.	356		630			
		ΑI	5,851,135	12/22/98	Sandhu et	al.	45		5			
		AJ	5,834,375	11/10/98	Chen		438		692			
		AK	5,730,642	03/24/98	Sandhu et	al.	451		6			
		AL	5,700,180	12/23/97	Sandhu et	al.	45		5			
		AM	5,667,424	09/16/97	Pan		451		6			
		AN	5,648,847	07/15/97	Ebbing		356		150			
		AO	5,643,050	07/01/97	Chen		451		10			
		AP	5,439,551	08/08/95	Meikle et	al.	438		5			
		AQ	5,433,651	07/18/95	Lustig et a	1.	451		6			
		AR	5,413,941	05/09/95	Koos et al	•	438		16			
		AS	5,337,144	08/09/94	Strul et al.		356		357			
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			ОТНЕ	R PRIOR A	RT (Including	Author, Title, Date, Pertinent Pa	ges, Etc.,)				
<u> </u>			Erkanat, Judy, "Applied Materials' Mirra chemical mechanical polishing system," Electronic									
DLY		AU	News 41 (2094): p.1, 1991									
		ΑV	Applied Materials, "Dielectric Deposition," http://www.appliedmaterials.com/products/pdd.html, printed 3/2/99									
320			intp.//www.appirouniateriais.com/producis/pdd.fittiff, printed 5/2/33									
EXAMINER DATE CONSIDERED												
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* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in												
	conformance and not considered. Include copy of this form with next communication to applicant(s).											